

Form PTO-1449 (Rev. 8-83)						U.S. Department of Commerce											
										Att'y. Docket No. D-21,389				Serial No.			
<b>Information Disclosure Citation</b>  (Use several sheets if necessary)										Applicants Belov et al.							
										Filing Date				Group			
U.S. PATENT DOCUMENTS																	
Examiner Initial		Document Number							Date	Name	Class	Subclass	Filing Date if Appropriate				
AD		6	4	3	6	8	3	5	8/2002	Kido et al.	438	693					
		6	4	4	3	8	1	1	9/2002	Nojo et al.	451	41					
		6	4	7	1	7	3	5	10/2002	Misra et al.	51	308					
		0	1	4	2	6	0	0	10/2002	Jacquinet et al.*	438	690					
		0	1	9	5	4	2	1	12/2002	Srinivasan et al.*	216	38					
		0	0	0	6	3	9	7	1/2003	Srinivasan et al.*	252	79.1					
AD		6	5	4	4	8	9	2	4/2003	Srinivasan et al.	438	692					
AD		0	1	7	1	0	7	2	9/2003	Ward et al.*	451	28					
FOREIGN PATENT DOCUMENTS																	
		Document Number							Date	Country	Class	Subclass	Translation Yes    No				
AD		8	4	6	7	4	0	6/1988	EP	-	-						
Other Documents (including Author, Title, Date, Pertinent Pages, Etc.)																	
AD		Zhao et al, "Direct CMP for STT", Semiconductor International (2001) pp. 145-150															
		Bonner et al, "Improved Direct Polish STI CMP Process with High Selectivity Slurry:Reduced Microscratching & Increased Productivity", Proceedings of 2002 CMP-MIC, pp 247-254															
		Garliardi et al, "Fixed Abrasives and Selective Chemistries:Some Real Advantages for Direct STI CMP", Proceedings of 2002 CMP-MIC, pp 288-290															
		Tseng et al., "STI CMP Process with High - Selectivity Slurry", Proceedings of 2002 CMP-MIC, pp. 255-259															
AD		Leduc et al, "CMP:Aiming for Perfect Planarization", Proceedings of 2002 CMP-MIC, pp 239-246															
AD		Devriendt et al, "Challenges for the Integration of Shallow Trench Isolation", Proceedings of 2003 CMP-MIC, pp 492-500															
EXAMINER: Anthony Opini								Date Considered 2/7/05									
* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in																	



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